

NATIONAL UNIVERSITY OF SINGAPORE

CIBA/RA/Eq/008		Experiment-Based Risk Assessment Form	
Name of Department	Physics	Location of Lab	S7-01-09
Name of Laboratory	CIBA chemistry lab	Name of PI	Mark Breese
Name of Researcher/LO	Mallikarjuna Rao Motapothula	Name of Activity/Experiment	silicon wafer polishing

No	Description/Details of Steps in Activity	Hazards	Possible Accident / Ill Health & Persons-at-Risk	Existing Risk Control (Mitigation)	Severity	Likelihood (Probability)	Risk Level	Additional Risk Control	Person Responsible	By (Date)
1	Switch on the power to the Polishing Machine	finger scratches, flying small, sharp objects if used incorrectly	bruised & cut fingers. Injuries from small flying bodies	1. Wear mask to prevent injury from splashes and flying bodies, wear gloves to prevent finger scratches.	1	1	1		Mallikarjuna Rao Motapothula	4/7/2010
2	Open the water tap			Training of staff not to rotate polishing wheel at high speeds	1	1	1			
3	start using the machine with required rpm				1	1	1			
4							0			
5							0			
6							0			
7							0			
8							0			
9							0			
10							0			

Conducted By Mallikarjuna Rao Motapothula

Approved By

Name Mark Breese

Signature _____

Approval date _____

Next Revision date _____
(Maximum 3 years)